

ECE-606

Homework No. 11 Assigned: Nov. 27 Due: Dec. 4

- 1) Consider an MOS capacitor on a p-type silicon substrate. The oxide capacitance is $2 \times 10^{-7} \text{ F/cm}^2$, the metal-semiconductor work function is -1V and a positive charge $Q_F = 8 \times 10^{-8} \text{ C/cm}^2$ resides at the interface. There is no charge in interface states. Using the above information calculate the following quantities.
 - a. Flat-band voltage
 - b. Electric field in oxide when the capacitor is biased at flat-band
 - c. If the acceptor density is 10^{16} cm^{-3} , calculate the surface potential that would be required to make the electric field in the oxide exactly equal to zero.
- 2) Solve SDF 17.2
- 3) Solve SDF 17.9
- 4) In a short channel MOSFET, the threshold voltage decreases with decreasing channel length and increasing drain-source bias. Explain these two effects and describe how you can minimize it.
- 5) For a MOSFET operating in the sub-threshold regime, the reduction in gate voltage needed to reduce the drain current by one decade is defined as the “sub-threshold swing”. The units of S are mV/decade.

Using this definition, prove that the smallest value of S attainable at room temperature (300K) is 60mV/decade. What is the typical range of S in a modern MOSFET?

Bonus: Which modern device has a sub-threshold swing lower than 60mv/decade? Explain.

- 6) Explain concisely the following terms generally associated with short-channel MOSFETs.
 - a. Drain-induced-barrier-lowering (DIBL)
 - b. Gate-induced-drain-leakage (GIDL)
 - c. Lightly-doped-drain (LDD)
- 7) For the fabrication of an n-channel MOSFET, the starting material is a p-type silicon wafer of (100) orientation. Write down the process steps needed to fabricate a self-aligned MOSFET for integrated circuits.